

Slater & Matsil, L.L.P.RECEIVED
CENTRAL FAX CENTER

Suite 1000

17950 Preston Road

Dallas, Texas 75252-5793

Phone: 972-732-1001 Facsimile: 972-732-9218

MAR 08 2006

FACSIMILE COVER SHEET

To Examiner: Stephen D. Rosasco

Total Pages Sent: 12

Technology Center 1700

(including cover sheet)

Facsimile Number: (571) 273-8300

Transmission Date: March 8, 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICEApplicant: Schulze, *et al.*Docket No.: 115747-0003//
2002P50544US

Serial No.: 10/753,604

Art Unit: 1756

Date Filed: January 8, 2004

TITLE: Method For The Repair Of Defects In Photolithographic Masks For Patterning
Semiconductor Wafers**CERTIFICATION OF FACSIMILE TRANSMISSION**

I hereby certify that the following papers are being transmitted by facsimile to Mail Stop
Amendment at the U.S. Patent and Trademark Office at (571) 273-8300 on March 8, 2006:

- Certification of Facsimile Transmission (1 page)
- Amendment (11 pages)

Respectfully submitted,

Kristy Engeldahl
Legal Assistant**Confirmation Respectfully Requested**

This facsimile is intended only for the use of the address named and contains legally privileged and/or confidential information. If you are not the intended recipient of this telecopy, you are hereby notified that any dissemination, distribution, copying or use of this communication is strictly prohibited. Applicable privileges are not waived by virtue of the document having been transmitted by Facsimile. Any misdirected facsimiles should be returned to the sender by mail at the address indicated on this cover sheet.

RECEIVED
CENTRAL FAX CENTER

MAR 08 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Schulze, *et al.* Docket No.: 115747-0003//
2002P50544US
Serial No.: 10/753,604 Art Unit: 1756
Filed: January 8, 2004 Examiner: Stephen D. Rosasco
For: Method For The Repair Of Defects In Photolithographic Masks For
Patterning Semiconductor Wafers

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's Office Action mailed December 8, 2005. Please amend the above-referenced application as follows.